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Attorney Docket: 040021-0306769  
Client Reference: OPP 031059 US

**JAN 0 8 2007**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT APPLICATION of:

SEUNG-CHUL CHOI

Confirmation Number: 3859

Application No.: 10/735,912

Group Art Unit: 1763

Filed: December 16, 2003

Examiner: Jeffrie Robert Lund

Title: CHEMICAL VAPOR DEPOSITION APPARATUS AND METHOD

January 8, 2007

**AMENDMENT UNDER 37 C.F.R. §1.116**

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated September 7, 2006, the date for response to which being January 8, 2007, by the enclosed Petition for a One Month Extension of Time, Fee, and intervening weekend, please amend the above-identified application as follows:

01/09/2007 EFLORES 00000031 033975 10735912

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